AUG 11 1999 AUG TRADENMENT

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## CONTINUED PROSECUTION APPLICATION (CPA) UNDER 37 C.F.R. § 1.53(d) REQUEST TRANSMITTAL

# 11, CPA \$ 8/19/99 V-Varnall

at the state of th		
Address to:	Attorney Docket No.:	303.229US2
Assistant Commissioner for Patents Box CPA Washington, D.C. 20231	First Named Inventor:	Leonard Forbes
	Express Mail No.:	EL334875593US
	Total Pages (if by fax):	0

This is a request for filing a continuation application under 37 CFR § 1.53(d) of prior application Serial No. 09/132,157, filed on August 11, 1998, entitled SILICON-GERMANIUM DEVICES FOR CMOS FORMED BY ION IMPLANTATION AND SOLID PHASE EPITAXIAL REGROWTH.

The above-identified prior application in which no abandonment of, or termination of, proceedings has occurred, is hereby expressly abandoned as of the filing date of this request for a CPA. Please use all the contents of the prior application file wrapper, including the drawings, as the basic papers for the new application. (37 CFR 1.53(b) must be used for continuation-in-part applications or for applications where the prior application is not to be abandoned.)

Enter the amendment previously filed on \_ under 37 CFR 1.116, but unentered, in the prior application.
 X A Preliminary Amendment (7 pages) is enclosed.
 This application is filed by fewer than all the inventors named in the prior application, 37 CFR 1.53(d)(4).
 a. \_ DELETE the following inventor(s) named in the prior nonprovisional application:
 b. \_ The inventor(s) to be deleted are set forth on a separate sheet attached hereto.
 A new power of attorney is enclosed.
 Information Disclosure Statement is enclosed.

08/10/1999 SLUREGI 00000024 09132157

b. \_\_\_

01 FC:131 02 FC:102 760.00 CP 156.00 OP

Form(s) 1449

Copies of IDS Citations

AUG 17 1999

CONTINUED PROSECUTION APPLICATION (CPA) REQUEST TRANSMITTAL Inventors: Leonard Forbes

Prior Application No.: 09/132,157

The filing fee is calculated below on the basis of the claims existing in the prior application as amended at 1 and 2 on the previous page:

	No. Filed	No. Extra	Rate	Fee
TOTAL CLAIMS	13 - 20 =	0	x 18 =	\$0.00
INDEPENDENT CLAIMS	5 - 3 =	2	x 78 =	\$156.00
[ ] MULTIPLE DEPENDENT CLAIMS PRESENTED				
BASIC FEE				
TOTAL				

	IUIAL		\$910.00			
6	Small Entity Status:					
	a A small entity statement is enclosed.	31				
	b A small entity statement was filed in the prior nonpr proper and desired.	ovisional application and such st	atus is still			
	c Is no longer claimed.	五	IJ EV			
7. <u>X</u>	A check in the amount of \$\_\$916.00 is attached to pay the fil	ling fee.	1999 ED			
8. <u>X</u>						
9	A petition for extension of time in the prior application is enclosed along with a check in the amount of \$0.00 to pay the extension fee.					
10	Other:					
	VEGMAN, LUNDBERG, WOESSNER & KLUTH, P.A. Fox 2938, Minneapolis, MN 55402 (612-373-6900)	By: No. 40,697	- Jagor			
Custo	mar Number 21186					

"Express Mail" mailing label number <u>EL334875</u>	5593115	Date of Deposit August 11, 1999
I hereby certify that this paper or fee is being der	posited with the United States Postal Service "Expres	s Mail Post Office to Addressee" service under
37 C.F.R. 1.10 on the date indicated above and is	s addressed to Box CPA, Assistant Commissioner for	Patents, Washington, D. C. 20231
Chris Hammond		is Hammond
Printed Name	Signature	

S/N 09/132,157

**PATENT** 

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant:

Leonard Forbes

Examiner: Mark Prenty

Serial No.:

09/132,157

Group Art Unit: 2822

202 2027

Filed:

August 11, 1998

Docket: 303.229US2

Title:

SILICON-GERMANIUM DEVICES FOR CMOS FORMED BY ION

IMPLANTATION AND SOLID PHASE EPITAXIAL REGROWTH

PRELIMINARY AMENDMENT

Assistant Commissioner for Patents Washington, D.C. 20231

Applicant has reviewed the final Office Action mailed May 28, 1999. Please amend the above-identified application as follows.

IN THE CLAIMS

Please cancel claim 33-37. Please amend claims 11, 24, 25, 28 and 30 as follows:

11. (Twice Amended)

A semiconductor transistor, comprising:

AUG 17 199

a silicon substrate;

a gate oxide, coupled to the substrate;

a gate, coupled to the gate oxide;

source/drain regions formed in the substrate on opposite sides of the gate; and

a Si<sub>1-x</sub>Ge<sub>x</sub> channel region, having a germanium molar fraction of x, and formed in the substrate, underneath and [adjacent]adjoining the gate oxide and between the source/drain regions;

wherein the  $Si_{1-x}Ge_x$  channel region has a channel length less than  $7\mu m$ .

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